



EE C245 - ME C218
Introduction to MEMS Design
Fall 2011

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Lecture Module 14: Sensing Circuits

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Lecture Outline

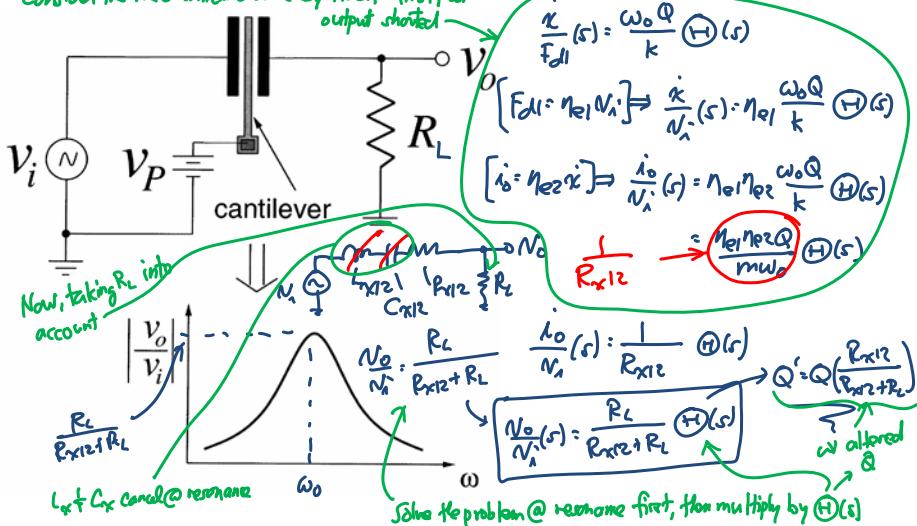
- Reading: Senturia, Chpt. 14
- Lecture Topics:
 - ↳ Detection Circuits
 - Velocity Sensing
 - Position Sensing

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Velocity-to-Voltage Conversion

- To convert velocity to a voltage, use a resistive load

Consider the mechanical device by itself first, we



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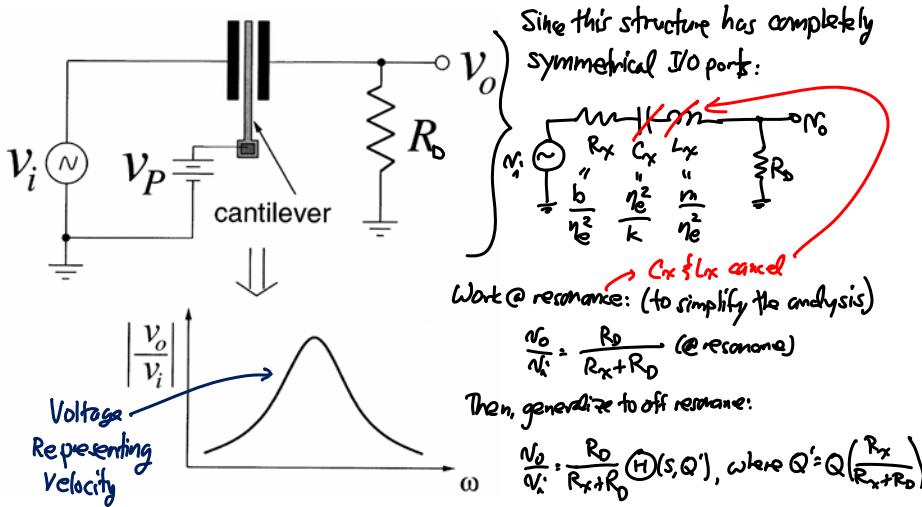
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Velocity-to-Voltage Conversion

- To convert velocity to a voltage, use a resistive load



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Velocity-to-Voltage Conversion

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- To convert velocity to a voltage, use a resistive load

Since this structure has completely symmetrical I/O ports:

$$Q = \frac{\omega_0 L_x}{R_x} \rightarrow Q' = \frac{\omega_0 L_x}{R_x + R_D} \rightarrow \frac{R_x + R_D}{L_x} = \frac{\omega_0}{Q'}$$

Brute force approach:

$$\frac{N_0(s)}{V_i} = \frac{R_D}{R_x + \frac{1}{sC_x} + sL_x + R_D} = \frac{sR_x C_x}{sR_x C_x + 1 + sL_x C_x + sR_D C_x} = \frac{s \frac{R_D}{L_x}}{s^2 + s \frac{R_x + R_D}{L_x} + \frac{1}{L_x C_x}}$$

$$= \frac{R_D}{R_x + R_D} \frac{s \left(\frac{R_x + R_D}{L_x} \right)}{s^2 + s \left(\frac{R_x + R_D}{L_x} \right) + \frac{1}{L_x C_x}}$$

$$\Rightarrow \frac{N_0(s)}{V_i} = \frac{R_D}{R_x + R_D} \frac{s (\omega_0 / Q')}{s^2 + s (\omega_0 / Q') + \omega_0^2} = \frac{R_D}{R_x + R_D} H(s, Q')$$

$Q' = Q \left(\frac{R_x}{R_x + R_D} \right)$

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Position-to-Voltage Conversion

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- To sense position (i.e., displacement), use a capacitive load

Again, here port-to-port I/O symmetry:

Brute force approach:

$$\frac{N_0(s)}{V_i} = \frac{\frac{1}{sC_D}}{R_x + \frac{1}{sC_x} + sL_x + \frac{1}{sC_D}}$$

$$\Rightarrow \frac{N_0(s)}{V_i} = \frac{\frac{1}{sC_D}}{sR_x C_x + 1 + s^2 L_x C_x + \frac{1}{sC_D}} = \frac{\frac{1}{sC_D}}{1 + \frac{sR_x C_x}{1 + C_x / C_D} + s^2 \frac{L_x C_x}{1 + C_x / C_D}}$$

$$\Rightarrow \frac{N_0(s)}{V_i} = \frac{\frac{1}{sC_D}}{1 + \frac{sR_x C_x}{1 + C_x / C_D} + s^2 \frac{L_x C_x}{1 + C_x / C_D}}$$

$$= \frac{C_x / C_D}{1 + C_x / C_D} \frac{\frac{1}{sC_D}}{s^2 + s \left(\frac{R_x}{L_x} \right) + \frac{(1 + C_x / C_D)}{L_x C_x}}$$

$$\left[\omega_0^2 = \frac{1}{L_x C_x} \rightarrow (\omega_0')^2 = \omega_0^2 (1 + C_x / C_D) \right]$$

$$\left[Q' = \frac{\omega_0' L_x}{R_x} = \frac{R_x}{L_x} \cdot \frac{\omega_0'}{Q'}, Q' = Q \sqrt{1 + C_x / C_D} \right] \text{ over } \rightarrow$$

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Position-to-Voltage Conversion

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- To sense position (i.e., displacement), use a capacitive load

$$\frac{V_o}{V_i}(s) = \frac{C_x/C_0}{1 + C_x/C_0} \frac{(w_0')^2}{s^2 + (w_0'/Q')s + (w_0')^2}$$

To maximize gain $\rightarrow 1$, need $C_0 \ll C_x$.
 (must minimize C_0)

Note: Can we similar short-cut to the R case.

- ① Get DC response $\rightarrow C$'s dominate.
- ② Then:

$$\frac{V_o}{V_i}(s) = (\text{DC Gain}) \cdot \frac{1}{s} \cdot \Theta(s, w_0', Q') \cdot w_0' Q'$$

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Velocity Sensing Circuits

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Velocity-to-Voltage Conversion

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- To convert velocity to a voltage, use a resistive load

Since this structure has completely symmetrical I/O ports:

Work @ resonance: (to simplify the analysis)

$$\frac{V_o}{V_i} = \frac{R_D}{R_x + R_D} \quad (@\text{resonance})$$

Then, generalize to off resonance:

$$\frac{V_o}{V_i} = \frac{R_D}{R_x + R_D} H(s, Q'), \text{ where } Q' = Q \left(\frac{R_x}{R_x + R_D} \right)$$

Voltage Representing Velocity

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Problems With Purely Resistive Sensing

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Now, we get: (approximately)

$$\frac{V_o}{V_i}(s) \sim \frac{R_D}{R_x + R_D} \cdot \frac{1}{1 + \frac{s}{\omega_p}} \cdot H(s, \omega_b, Q')$$

$\omega_p = \frac{1}{(R_x || R_D)C_p}$

Depend on both R_D & C_p .

Impact depends on where ω_p is relative to ω_0 .

Not Good

Okay

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Problems With Purely Resistive Sensing

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- In general, the sensor output must be connected to the inputs of further signal conditioning circuits \rightarrow input R_i of these circuits can load R_D

These change w/ hook-up \rightarrow not good.

Problem: need a sensing circuit that is immune to parasitics or loading.

Soln: use op amps.

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The TransR Amplifier Advantage

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- The virtual ground provided by the ideal op amp eliminates the parasitic capacitance C_p and R_i
- The zero output resistance of the (ideal) op amp can drive virtually anything

Virtual Ground
 \Rightarrow No voltage across C_p
 $\hookrightarrow C_p$ effectively isn't there!

$V_0 = -\frac{R_2}{R_x} H(s) i_1$

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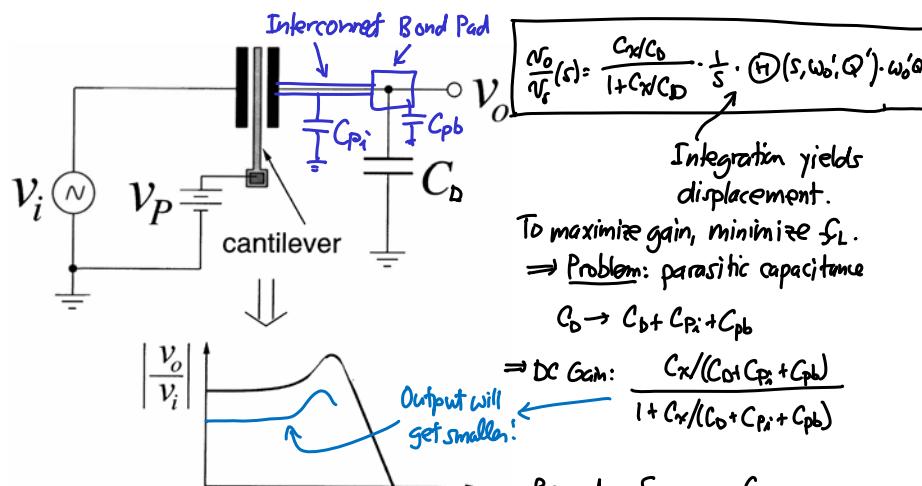
Position Sensing Circuits

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Problems With Pure-C Position Sensing

- To sense position (i.e., displacement), use a capacitive load



$$\frac{V_O}{V_i} = \frac{C_D/C_D}{1+C_X/C_D} \cdot \frac{1}{s} \cdot H(s, \omega_0, Q') \cdot \omega_0 \alpha$$

Integration yields displacement.

To maximize gain, minimize f_L .
 ⇒ Problem: parasitic capacitance
 $C_D \rightarrow C_D + C_{Pi} + C_{Pb}$

⇒ DC Gain: $\frac{C_X/(C_D + C_{Pi} + C_{Pb})}{1 + C_X/(C_D + C_{Pi} + C_{Pb})}$

Output will get smaller!
 Remedy: Suppress C_p via use of op amps.

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The Op Amp Integrator Advantage

The diagram shows a MEMS mass-spring system. A mass m is attached to a spring with stiffness k , which is fixed to a wall. The mass is positioned between two electrodes, Electrode 1 and Electrode 2. The distance from the wall to the center of the mass is b . The distance from the wall to the top of Electrode 1 is d_1 , and the distance from the bottom of Electrode 2 to the center of the mass is d_2 . A force F_{dl} acts on Electrode 1. A voltage source v_1 is connected to Electrode 1, and a voltage V_P is connected to ground. The output current from Electrode 1 is i_1 . A capacitor C_1 is shown between Electrode 1 and ground. The output current from Electrode 2 is i_0 . A capacitor C_p is shown between Electrode 2 and ground. The output voltage v_0 is taken from the non-inverting input of an operational amplifier. The inverting input is grounded. A feedback resistor R_2 is connected between the output v_0 and the inverting input. A capacitor C_2 is connected between the inverting input and ground.

- The virtual ground provided by the ideal op amp eliminates the parasitic capacitance C_p

$N_o = -i_0 \left(R_2 \parallel \frac{1}{sC_2} \right)$

$\approx -\frac{V_i}{R_X} \frac{1}{sC_2} \xrightarrow{\text{well defined}} \frac{N_o}{N_s}(s) = -\frac{1}{R_X C_2} \frac{H(s)}{s}$

$R_o = 0\Omega$

Can drive next stage's R_i w/o interference to transfer function!

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Differential Position Sensing

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Differential Position Sensing

Example: ADXL-50

Tethers with fixed ends

Proof Mass

Sense Finger

Applied Acceleration

Fixed Electrodes

V_p

C_1

C_2

V_o

C_p

Capacitive divider

$V_o = -V_p + \frac{2V_p}{C_1+C_2}$

$$= -\frac{V_p C_1 - V_p C_2 + 2V_p C_1}{C_1+C_2} = V_p \left(\frac{C_1 \cdot C_2}{C_1+C_2} \right) = V_o$$

Issue: Parasitic Capacitance

$$V_o = \frac{C_1 \cdot C_2}{C_1+C_2+C_p} V_p$$

Suspension Beam in Tension

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Buffer-Bootstrapped Position Sensing

$+V_p$

$-V_p$

V_o

C_p

C_{gd}

Unity Gain Buffer

$C_{gd} = \text{gate-to-drain capacitance of the input MOS transistor}$

Includes capacitance from interconnects, bond pads, and C_{gs} of the op amp

- Bootstrap the ground lines around the interconnect and bond pads
 - No voltage across C_p
 - It's effectively not there!

Interconnect

Ground Plane

1x

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Effect of Finite Op Amp Gain

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Total ADXL-50 Sense $C \sim 100\text{fF}$

$$+V_P \quad -V_P \quad N_o = A_o(N_i^+ - N_i^-) = A_o(N_i^+ - N_o) \rightarrow N_o(1 + A_o) = A_o N_i^+ \rightarrow \frac{N_o}{N_i^+} = \frac{A_o}{1 + A_o}$$

$$\text{Get } Z_i = \frac{V_i}{i_i}: \quad i_i = (N_i^+ - N_o) s C_p = N_i^+ \left(1 - \frac{A_o}{1 + A_o}\right) s C_p = N_i^+ \frac{1}{1 + A_o} s C_p$$

$$\therefore \frac{N_i^+}{i_i} = Z_i = \frac{1}{s \left[\frac{C_p}{1 + A_o} \right]} \quad \boxed{C_{eff} = \frac{C_p}{1 + A_o}}$$

No longer zero!

Ex: $A_o = 100, C_p = 2\text{pF}$
 $\Rightarrow C_{eff} = \frac{2\text{p}}{101} = 20\text{fF}$

Not negligible compared w/ ADXL-50 $C_{tot} \sim 100\text{fF}$!

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Integrator-Based Diff. Position Sensing

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+V_P i_1 $\frac{1}{C_1}$
-V_P i_2 $\frac{1}{C_2}$

$$i_o = i_1 + i_2 = N_p(sC_1) - N_p(sC_2) = V_p s(C_1 - C_2)$$

$$\therefore N_o = -i_o \left(\frac{1}{sC_F} \right) = -N_p \left(\frac{C_1 - C_2}{C_F} \right)$$

$$\boxed{\frac{N_o}{V_p} = -\frac{C_1 - C_2}{C_F}}$$

(for biasing)

$R_2 \gg \frac{1}{sC_2}$

$R_o = 0\Omega$

Can drive next stage's R_i w/o interference to transfer function!

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